

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

First Named  
Inventor :

Benjamin Y.H. Liu et al.

Appln. No. : 10/769,011

Filed : January 30, 2004

For : HIGH-PERFORMANCE AND MULTI-  
LIQUID-PRECURSOR  
VAPORIZATION IN  
SEMICONDUCTOR THIN FILM  
DEPOSITION

Group Art Unit: 1763

Examiner: Richard Bueker

Docket No.: M419.12-0043

**REQUEST FOR APPROVAL OF FORMAL DRAWINGS**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

I HEREBY CERTIFY THAT THIS PAPER  
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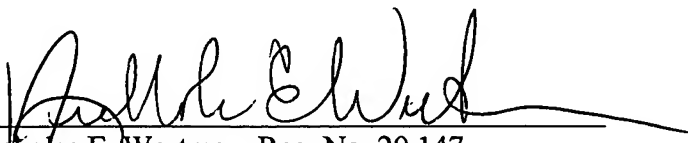
  
PATENT ATTORNEY

Sir:

Enclosed are **Eight (8)** sheets of formal drawings for filing in the above-identified application.

Respectfully submitted,

WESTMAN, CHAMPLIN & KELLY, P.A.

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NEW:rkp